Docket No.: SHIGA-006

n the Specification

Kindly replace the ABSTRACT with the following:

The plastic film electrostatic adsorption apparatus of the present invention comprises an electrostatic adsorption electrode, an insulated dielectric layer that covers the electrostatic adsorption electrode and has a center line average roughness of an adsorption surface on which a plastic film is placed of 0.5 micrometers or less, and a power supply electrode that applies a voltage to the electrostatic adsorption electrode. According to this plastic film electrostatic adsorption apparatus, surface treatment can be performed even in a vacuum without requiring tedious work such as application or removal of adhesive. In addition, even if the plastic film expands and deforms due to heat treatment and plasma treatment performed during surface treatment, there is no occurrence of wrinkling, deformation or separation in the plastic film due to the difference in thermal expansion between the electrostatic adsorption surface and plastic film.

Kindly amend the third paragraph on page 7 as follows:

Electrostatic adsorption apparatus 10 of this example has a structure in which electrostatic adsorption electrode 3, composed of positive electrode 1 and negative electrode 2 formed on the surface of insulated dielectric layer 5, is covered with insulated dielectric layer 4. In addition, insulated dielectric layer 4 has electrostatic adsorption layer 6, which electrostatically adsorbs plastic film 20 placed thereon, on the surface of insulated dielectric layer 4. In addition, Electrostatic electrostatic adsorption apparatus 10 is equipped with power supply electrode 7 that applies voltage to electrostatic adsorption electrode 3.